

IN THE CLAIMS:

Please amend the claims as follows:

1.(Amended) A film deposition apparatus comprising:

a stock chamber for loading or unloading a substrate;

a transferring chamber including a mechanism for transferring said substrate; and

a liquid phase film deposition chamber connected to said transferring chamber through a gate,

wherein said liquid phase film deposition chamber is provided with a mechanism for oxidizing an element belonging to Group 1 or 2 of the periodic table.

13.(Amended) A film deposition apparatus comprising:

a stock chamber for loading or unloading a substrate;

a transferring chamber for transferring said substrate; and

an EL material deposition chamber connected to said transferring chamber through a gate,

wherein said EL material deposition chamber is provided with a cell which contains an element belonging to Group 1 or 2 of the periodic table.

Cancel Claims 19-30.

REMARKS

Applicants are merely correcting typographical errors in the claims and canceling the non-elected claims. It is not believed that any fee is necessary for the amendment. If any fee is due for this submission, please charge our deposit account 50/1039.